$\begin{array}{c} \text{Tabletop Microscope} \\ \text{TM4000 } \mathbb{I} / \\ \text{TM4000Plus } \mathbb{I} \end{array}$

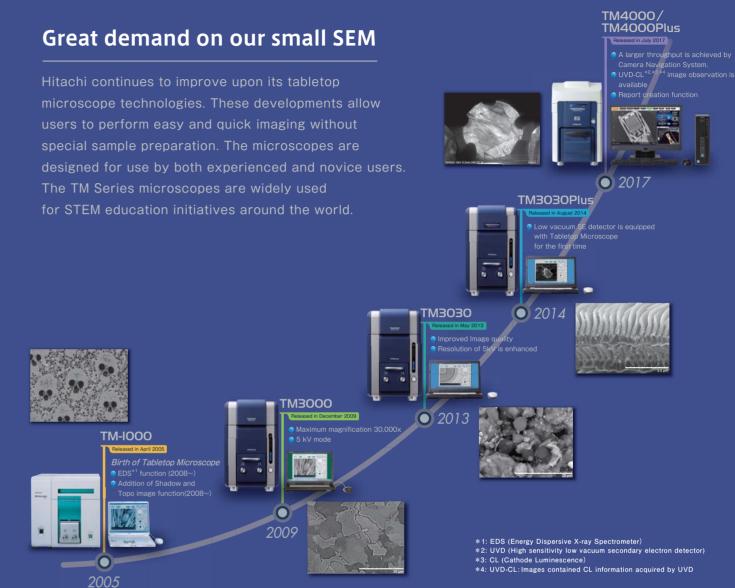




Gateшay to Innovation.



History of Hitachi Tabletop Microscope Series.

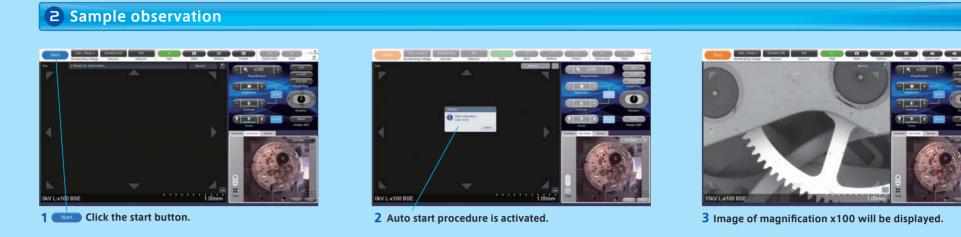


Easy & intuitive operation	A quality image can be obtained with simple steps.	▶ P3	Low vacuum SE detector	Low vacuum SE detector providing surface detail and topography.	TM4000PlusⅡ ▶ P9
No sample preparation	Non-conductive sample observation under low vacuum status.	▶ P5	Image mixing (BSE+SE)	Simultaneous imaging of various information.	TM4000PlusⅡ ▶P11
High-sensitivity BSE detector	Various imaging applications using 4-segment BSE detector.	≻ P7	Features	 20 kV accelerating voltage for imaging and analytical capab Multi Zigzag for large area or 	ilities. ▶P12

The image on the screen includes options. *Option

A quality image can be obtained with simple steps.



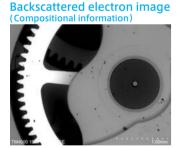


Within several minutes to obtain an image.

Automation, Observation, and Elemental Analysis



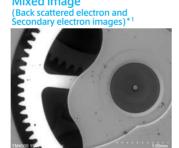
Easy to switch images with one-click.









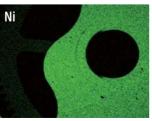


Rapid acquisition of elemental maps*2









Sample: Movement of watch

*1 Secondary electron images and MIX images can only be observed in TM4000Plus II

Intuitive operation on Camera Navi*



Use of optical images helps navigate to target observation area easily. Obtained SEM images can be layered on a SEM MAP image.











*Option: Camera Navigation System

Report Creator



Simply select images and a template to create a customized reports. Created reports can be saved/edited in Microsoft Office® formats.



The image on the screen includes options.

3 Tabletop Microscope TM4000 Series Tabletop Microscope TM4000 Series 4

Non-conductive sample observation under low vacuum status.



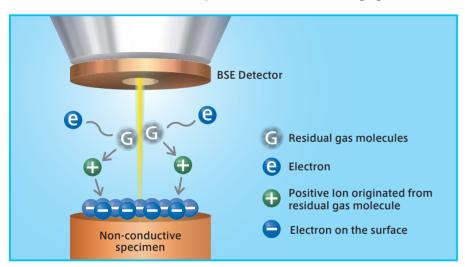
Simple observation on water/oil contained samples

When a non-conductive sample is observed under a high-vacuum state, electrons accumulate on the sample surface causing a charging phenomenon, which prevents imaging. In order to reduce phenomenon, samples are usually coated with a thin layer of conductive material prior to observation. This process is not only time consuming, but also interferes with imaging of surface details as well as EDS analysis. The TM4000 II is equipped "Charge-up reduction mode" for saving your time and removing the interferes.



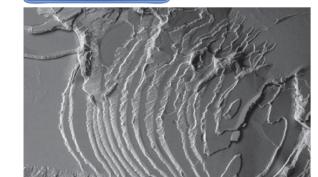
Low-vacuum microscopy

By utilizing a lower vacuum level inside the specimen chamber, more gas molecules are present. These gas molecules 🕝 collide with the electron beam to generate positive ions 🕀 and electrons 😉 Each positive ion 🕣 can be neutralized by one of the excess electrons 🔵 on the specimen surface. This way, the excess electrons on the surface of the sample are removed and the charging is eliminated or reduced.





Observation without coating



Accelerating voltage: 10 kV

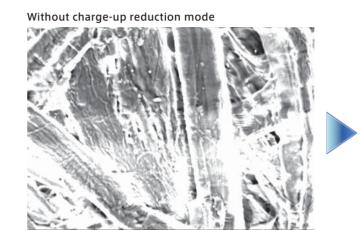
Non-conductive sample

Sample: Fracture surface of Resir



Charge-up reduction mode

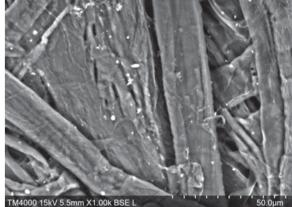
Charge on a sample can be reduced by one-click.



Accelerating voltage: 15 kV Image signal: BSE Magnification: 1,000x



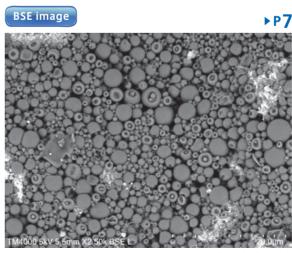
Charge-up reduction Mode



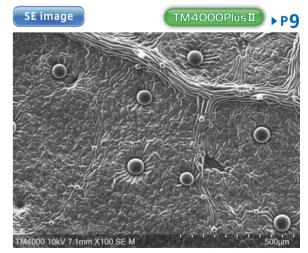
Accelerating voltage: 15 kV Image signal: BSE

Image a variety of materials under low vacuum condition

The images show observations of non-conductive samples such as ink toner particles and a hydrated leaf surface.



Accelerating voltage: 5 kV Image signal: BSE Magnification: 2,500x



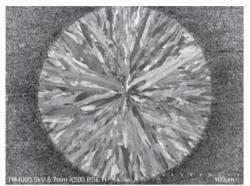
Accelerating voltage: 10 kV Image signal: SE Magnification: 100x

Various imaging applications using 4- segment BSE detector.

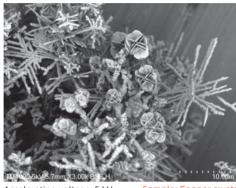
Composition/ Fine structure

Compositional contrast and fine structure observation

The TM4000 Series is equipped with a high-sensitivity four-segments BSE detector which is used to observe the different brightness levels representing composition in the sample or traditional topographic imaging.



Accelerating voltage: 5 kV Sample: Metal will Image signal: BSE Magnification: 500x



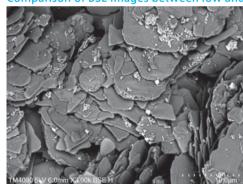
Accelerating voltage: 5 kV Sample: Copper cryst Image signal: BSE Maghification: 3,000x

5 kV BSE*

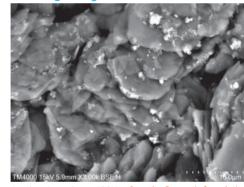
Compositional contrast including surface details using lower accelerating Voltage

Under lower accelerating voltage conditions, the electron signals are generally reduced due to loss of emission and brightness. The TM4000 II Series optimizes the emission across the voltage range to maintain a higher brightness level, even at the lower 5 kV accelerating voltage.

Comparison of BSE images between low and high accelerating voltages



Accelerating voltage: 5 kV Image signal: BSE Magnification: 3,000x



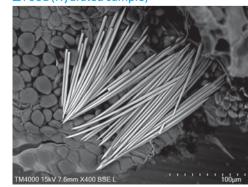
Accelerating voltage: 15 kV Sample: Cosmetic foundat Image signal: BSE Magnification: 3,000x

*BSE (Backscattered Electron)

Application example

Observation examples using BSE detector

■ Food (Hydrated sample



Accelerating voltage: 15 kV Image signal: BSE

Sample: Chinese

■ Electronic components (Grain contrast)



Image signal: BSE
Magnification: 1,500x

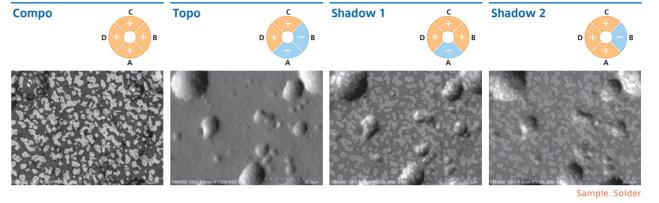
Sample: Au Bonding Wire Sample treated by Hitachi ion milling system

Multi image observation

Multiple images observation

The TM4000 II Series features a backscattered-electron detector with four fully controllable independent segments. By utilizing the segments in different combinations, it is possible to emphasize compositional or topographical detail from the sample, as well as producing 'shadowed' images which highlight the surface from multiple directions.



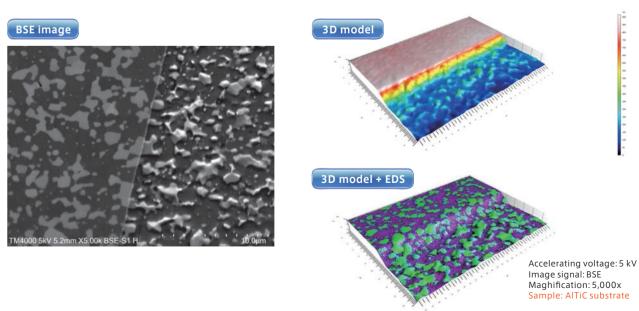




Three-Dimensional image display/ measurement function*

Hitachi map 3D

Three-dimensional images are obtainable without sample tilting or concerns about image shift since this 3D function utilizes the 4-segment BSE detector which can detect images from 4 distinct directions. Surface roughness can be measured easily based on the height measurement between 2 points (line profile), and the entire surface area (3D model).



*Option

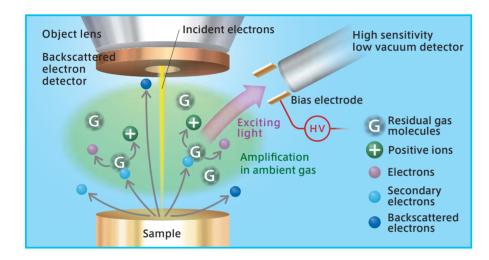
Low vacuum SE detector providing sur face detail and topography.

SE imaging under Low vacuum mode Innovative secondary-electron detector to obtain surface detail with non-conductive samples at lower vacuum conditions

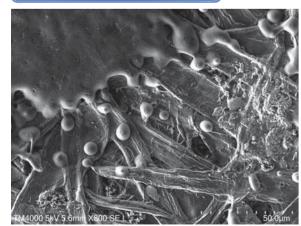
The TM4000Plus II can observe not only conductive samples, but also non-conductive or hydrated samples without sample preparation. Switching between BSE and SE can be performed easily.

High-sensitivity Low vacuum SE Detector (UVD)

Hitachi's UVD generates secondary-electron images by detecting visible light excited by the electron gas interactions.

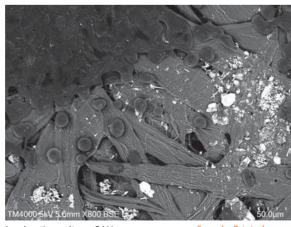


SE image (surface information)



Accelerating voltage: 5 kV Image signal: SE Magnification: 800x

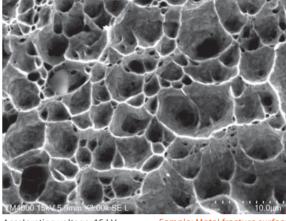
BSE image compotional information



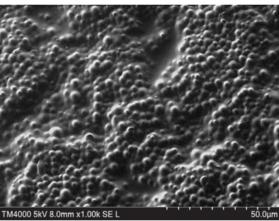
Accelerating voltage: 5 kV Image signal: BSE Magnification: 800x

Application data

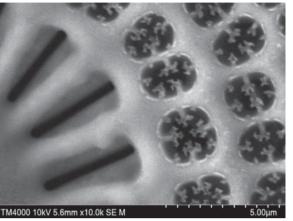
Fine surface structure observation



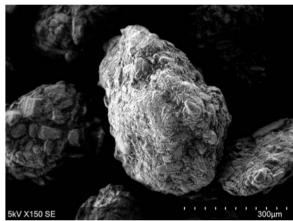
Accelerating voltage: 15 kV Sample: Metal fracture surface Image signal: SE Magnification: 3,000x



Accelerating voltage: 5 kV Image signal: SE Magnification: 1,000x



Accelerating voltage: 10 kV Image signal: SE Magnification: 10,000x



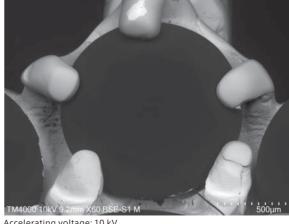
Accelerating voltage: 5 kV Image signal: SE Magnification: 150x

Sample: Powder Medicine

Application data

UVD-CL* image observation

UVD enables to obtain CL information instead of cathode luminescence (CL) detector. In addition, simultaneous imaging of BSE and UVD-CL becomes possible.



Accelerating voltage: 10 kV Image signal: BSE Magnification: 60x



Accelerating voltage: 10 kV Image signal: UVD-CL Magnification: 60x

*UVD-CL: Image contains CL information captured by UVD

- 20 kV accelerating voltage for improving both imaging and analytical capabilities.
- Multi Zigzag for large area or multiple areas.



A Single image includes both surface and compositional information

The BSE images shows the composition information and the SE image shows the surface information. By layering the both images in one image as a mixed image, the both composition and surface information of a sample can be observed in one image.



Accelerating voltage: 5 kV Magnification: 2,000x Sample: Sandpaper

information

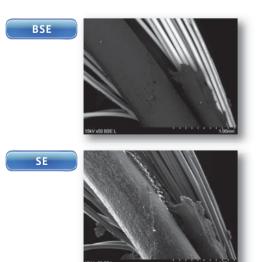
(SE)

(BSE + SE)

Application data

Advantage of mixing images

In addition to imaging of BSE and SE information, TM4000Plus II is capable of layering these images. Therefore, the both characteristic information can be viewed in on image. Furthermore, the BSE, SE and mixed image (BSE+SE) can be switched with one-click.



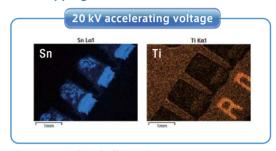


Accelerating voltage: 15 kV Magnification: 50x Sample: Power cord

Advantages of 20 kV accelerating voltage

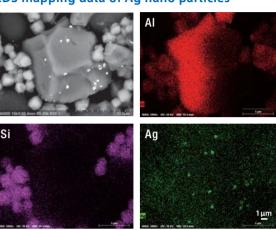
High accelerating voltage enables higher-speed EDS analysis.

EDS mapping data at 20 kV in 2 min



Sample: Electronic components

EDS mapping data of Ag nano particles



Magnification: 5,000x Sample: Sprayed powder

Multi Zigzag*

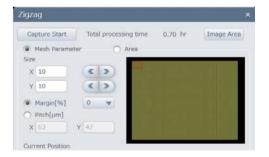
A function that takes multiple high-magnification images and stitches them together to create a single high-resolution image.

(Optical image)



Zigzag conditions

Setting matrix parameters for image array such as field of view, number of images, pitch, and overlay from menu.



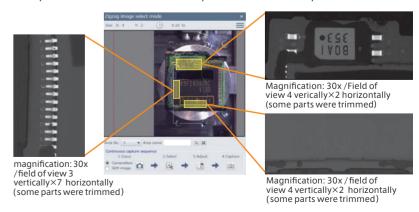
Stitching



Acceleration voltage: 15 kV Image signal: SE Magnification: 30x Field of view 10 vertically ×12 horizontally (some parts were trimmed)

Zigzag specification

Multiple fields and locations can be specified for each sample.



Sample: Electronic components

*Ontion for motor drive stage

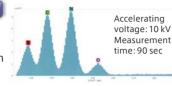
Various EDS for elemental analysis.

Ouantax 75

High energy resolution detector and advanced user friendly analysis software.

High-energy resolution detector

The high-energy resolution detector allows light elements such as boron to be analyzed with high accuracy.





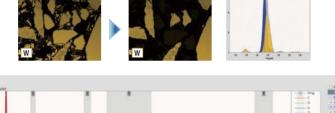
Produced by Bruker nano GmbH

Live deconvolution to separate overlapping elements

Allows spectra with overlapping peaks to be separated and visually mapped in real time.

Peak fitting function

Automatic background subtraction and peak fitting (automatic/arbitrary) provide highly reliable element identification. To be able to estimate the self-measurement conditions, electron beam penetration depth, spread, and density in the actual sample, it is possible to simulate the actual measurement area.

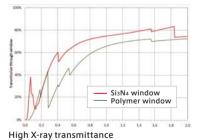


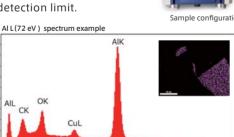
Element

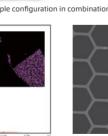
Advanced EDS features for tabletop SEM

Si₃N₄ Window

Si₃N₄ Window to optimize low energy X-ray transmission for light element analysis. Compared with conventional detector window, there is improved mapping speed and detection limit.









Extreme low energy detection

APEX Software

- · Easy to Interpret Data
- · Multi user logins
- · User configurable windows
- · Customizable reporting
- · Simplified automation
- · Fast mapping
- · Collect/Review simultaneously
- · Spectrum Match Libraries

Produced by EDAX Inc.



Hexagonal support grid for increased

Aztec Series

- · Live Spectrum Viewer with Automatically labelled peaks can be shown. (AZtecLiveOne)
- · High-throughput analysis with high-precision pile-up correction function and TruQ[™] Technologies.
- · TruMap generates element maps that peak overlaps removed in real time.





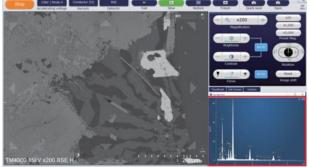


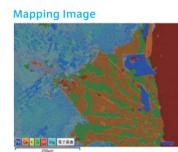
Live EDS function

Live Spectrum View is available on the TM4000 User Interface to see the X-ray spectrum with Automatically labelled peaks. It allows you to confirm elemental information with secondary

electron images and/or backscattered electron images, even while moving around your sample.

Live EDS spectrum





AZtecLiveOne

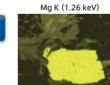
The TruMap feature allows multi-element spectra to be properly separated and background subtracted in real time, resulting in

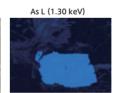
A7tecl iveOne: standard feature AZtecOne: Option

a precise elemental map with no image contamination due to overlapping peaks.

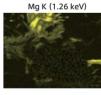
Typical ROI MAP

TruMap











Advanced Analysis

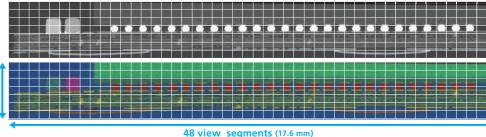
The AZtecEnergy system offers advanced analytical functionality and flexible configurations with an ability to automate analysis via a motorized stage.

AZtecEnergy

AztecEnergy enables large-area mapping and particle analysis.

Large-area mapping

The mapping software automatically acquires data for multiple specified regions to produce a single combined set of mapping information.



Magnifications: 400x Sample: Cross section of electronic compon

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Selection of stages.

Software option

Maintenance

Software for image post-processing. Easy maintenance.



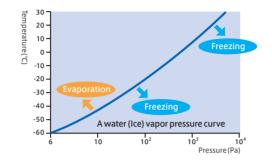
Cooling stage

Produced by Deben UK Ltd.

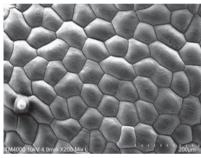
The cooling stage allows samples to be cooled to temperatures as low as -25 °C and kept at the temperature up to a few hours. It is particularly well suited for observation of hydrated samples such as foods and biological tissues, or samples susceptible to thermal damage.

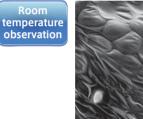












voltage: 10 kV



Tilt & Rotation stage

Produced by Deben UK Ltd.

Observation range of 15° to 60° tilting angles and full 360° rotation are available on the tilt and rotation stage.







Tilt: 45°+Rotation

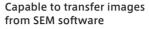


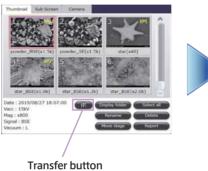


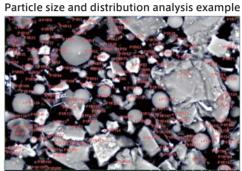
Accelerating voltage: 15 kV Image signal: BSE, Mix Magnification: 150x Sample courtesy of professor Tomoyuki Shimano, Hosei University

Image Processing, Measurement, and Analysis Software: Image Pro[®] for Hitachi

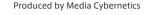
The TM4000 II features integration icon to transfer images into Image Pro® Software with a single click.



















Easy maintenance



Oil-free vacuum pump and pre centered cartridge filaments are equipped a standard.







Pre-centered

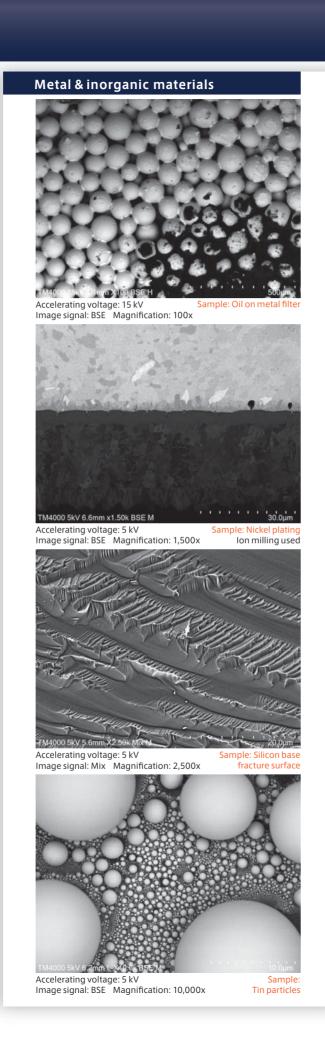
Maintenance kit available for your daily use.*

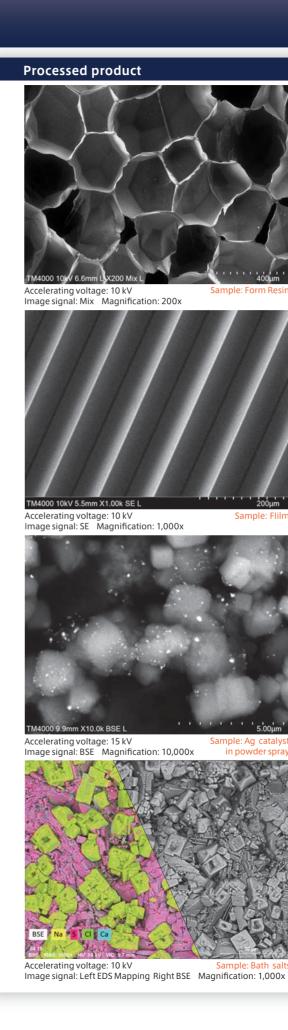


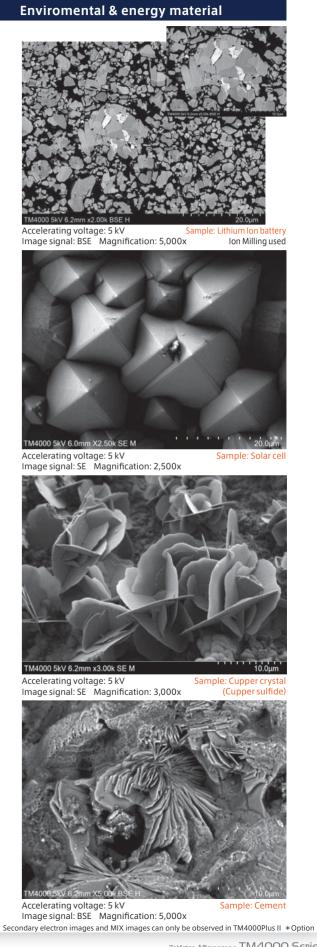
*Option

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Electronic components Accelerating voltage: 15 kV Image signal: SE Magnification: 30x Accelerating voltage: 5 kV Image signal: BSE Magnification: 5,000x Accelerating voltage: 15 kV Image signal: BSE Magnification: 20,000x







Minerals

Zircon UVD-CL*1 observation example

Following are BSE and UVD-CL images of a zircon cross section. Although the compositional difference cannot be confirmed from the BSE image, the UVD-CL image shows the difference via the striped pattern from the emission intensity. This zircon also contains apatite as an inclusion. Zr which is one of the components of "Zircon" and P which is the component of apatite are overlapped in each peak. Normally this combination of elements is difficult to identify with traditional EDS*2 mapping, but the distribution of Zr and P can be distinguished by using a peak separation mapping.

BSE Image



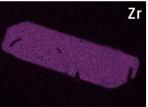
Accelerating voltage: 10 kV Magnification: 400x

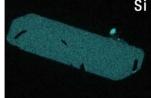
UVD-CL Image

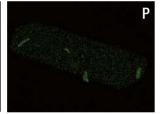


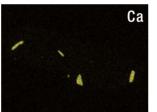
Accelerating voltage: 10 kV Magnification: 400x

EDS Mapping









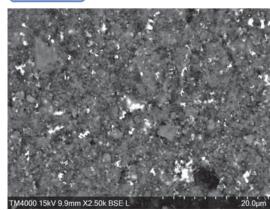
Sample: Zircon

Processed product

UVD-CL*1 observaiton for fluorescence brightener on paper

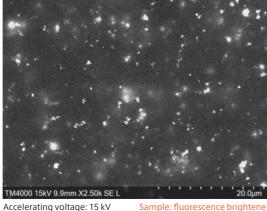
Dispersion of fluorescence brightener which is used for color development on paper is difficult to distinguish between SE and BSE detectors, but UVD-CL allows for these brightener particles to be visible.

BSE Image



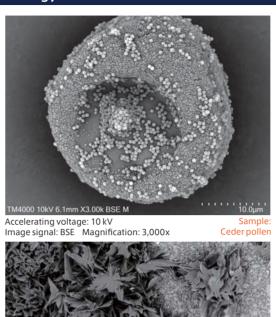
Accelerating voltage: 15 kV Magnification: 2,500x

UVD-CL Image



Magnification: 2,500x

Biology & foodstuffs & Medicine





Cooling stage used



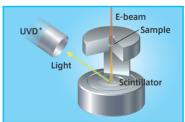
Accelerating voltage: 10 kV Image signal: BSE Magnification: 1,000x

Accelerating voltage: 5 kV Image signal: SE Magnification: 200x

STEM Holder

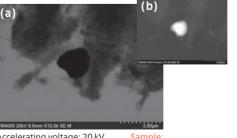
Easily obtain transmitted images on thin samples

The newly developed STEM holder can be used to perform transmission images with the Hitachi UVD. Images of thin or biological samples can be obtained.



*UVD is a function of





Accelerating voltage: 20 kV Sample: Image signal: (a) STEM, (b) BSE Abrasive Magnification: 10,000 x



Accelerating voltage: 15 kV Image signal: STEM Magnification: 1,000 x



Accelerating voltage: 15 kV Image signal: STEM Magnification: 5,000 x

UVD is function of TM4000Plus II *Option

*1 UVD-CL: Image contains CL information captured by UVD *2 Option

Application gallery

Workflow approach to asbestos analysis

The TM4000 II Series can count and analyze asbestos fibers by using EDS* along with Multi Zigzag.

Step1 > Locating fiber on filter

Multiple fields of view can automatically be captured .





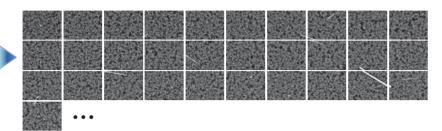
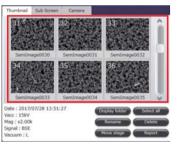
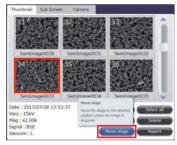


Image signal: BSE Magnification: 2,000x Sample: Tremolite (asbestos standard sample)

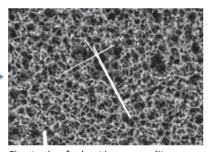
Step 2 > confirmation of fiber locations within matrix



Choose thumbnails with fibers

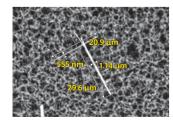


One click takes you to fiber of interest



Fine tuning for best image quality

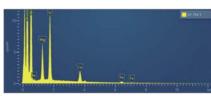
Step3 > Measuring the fiber diameter and elemental confirmation



Confirm aspect ratio and fiber length



Spot analysis for elemental confirmation



Get EDS Spectrum*

*Option

EDS specification (option)

Quantax75 specific	ation Made by Bruker nano GmbH
Detector	
Item	Description
Detector type	Silicon drift detector (SDD)
Detector area	30 mm ²
Energy resolution	148 eV(Cu-Kα)
	(Mn-Ka: equivalent of 129 eV or less)
Detection element	B ₅ ~Cf ₉₈
Cooling method	2-stage thermoelectric (peltier) cooling (without fan and LN2 free
Energy channel	4,096 channel (2.5 eV/ch at minimum)
Software	
Item	Description
Qualitative analysis	Auto/manual
Quantitative analysis	Standardless quantitative analysis, normalized to 100%
Analysis mode	Object mode (including point, rectangle, ellipse and polygon)
	Line scan
	Hypermap (mapping, spot analysis, line analysis)
Element mapping	Maximum map image resolution 1,600x1,200
	Rainbow map
	Online deconvolution
Report preparation features	Templates for printing may be prepared
	PDF, Microsoft® Word, Excel
Size/weight	
Item	Description
Detector	100 (width) × 45 (depth) × 120 (height) mm, 1.45 kg
Scaning control unit	225 (width) × 230 (depth) × 150 (height) mm, 3.65 kg
Installation conditions	
Item	Description
Power supply	Single-phase AC, 100/240 V 50/60 Hz

Element specifica	ation Made by EDA
Detector	
Item	Description
Window type	Silicon Nitride Windows
Type of Sensor	Silicon drift detector (SDD)
Sensor size	30 mm ²
Energy resolution	129 eV (Mn-Kα)
Detection range	Be ₄ ~Am ₉₅
Cooling system	Thermoelectric Peltier cooling (fan and LN free)
	No cooling required when not in use
Software	
Item	Description
Qualitative analysis	Auto/Manual, HPD
Quantitative analysis	Standardless Method, Graph view/Statistics display
Analysis mode	Spectrum (Point, Area, Free Draw, Grid)
	Linescan (Spectral Linescan, Review and Rebuild)
	X-ray Map (Spectral Map, Review and Rebuild)
X-ray Map	1,024×800 (Max.)
	Spectral Map (Review Spectrum, Line from Map, Rebuild N
	Comp Map (Real-time Peak deconvalution map)
	Quant Map (Concentration map)
	Drift Collection
Reporting	Report Template for Printing
	PDF, Microsoft® Word, Excel, PowerPoint
■ Size / weight	
Item	Description
PC Workstation	169 (width) × 435 (depth) ×356 (height) mm, 12 kg
Detector	100 (width) × 45 (depth) ×120 (height) mm, 0.5 kg
DPP Box	73 (width) × 171 (depth) ×121 (height) mm, 1.6 kg
■Installation conditions	
Item	Description
Power supply	Single-phase AC100/240 V 50/60 Hz

Aztec series speci	fication for TM4000 series		Made by Oxford Instruments NanoAnalysis
Detector			
Item	AZtecOne	AZtecLiveOne	AZtecEnergy
Detector Type	Silicon drift detector (SDD)		
Detector Area	30 mm ²		
Energy resolution	158 eV (Cu Ka) (Mn Ka: equivalent of 137 e	V)	
Detection Element	B₅~U ₉₂		
Thermal Cycle	Detector cool down on demand		
Cooling Method	2 stage thermoelectric cooling (without fan/L	N ₂ free)	
Software			
Item	AZtecOne	AZtecLiveOne	AZtecEnergy
Live spectrum		Live Spectrum Monitor on Viewer window	Live Spectrum Monitor on Mini View
	_	with automatically labelled peak	with automatically labelled peak
Spectrum display	Scaling display in horizontal and vertical direct		
Qualitative analysis	Auto / Manual by TruQ [™] technology, Pulse F		,
Quantitative analysis	Standard less analysis by XPP correction, 100		
Image acuisiton	2,048×1,536, 1,024×768, 512×384		64 - 8,192 pixels
Element mappping	1,024×768, 512×384, 256×192, 128×96, T	iled or Lavered view	64 - 4,096 pixels
	layered Image: No limit on the number of X-ra	-	layered Image: No limit on the number of X-ray maps that can be overlaid
	Reconstruct Spectrum from mapping during/al		on SEM image Reconstruct Spectrum from mapping during/after acquisiti
Line Scan	Arbitrary line position and direction may be sp		
	Linescans can be viewed in a Vertical tiled,St	acked or table of values Spectra can be reco	onstructed from any point on the linescan
Point & ID	Acquire from point, rectangle, ellipse or freeha	and	
	Overlap a spectrum from any project in the Da	ata Tree over the current spectrum	
TruMap		Overlap and background corrected mapping	anti-mal.
	optional	and LineScanning during/after acquisition	optional
Assistance	Operation guide functionality		
Data management	Data saved in individual projects		
Report preparation	Quick and easy reporting functionality		Comprehensive list of Report templates that can be exported in Word
	· Content selectable via radial buttons		and Excel format
	· Exports in Microsoft® Word format (reports of	an be viewed in free Microsoft viewer)	Image, Maps and Spectra can be saved as selectable image files
			with user control over resolution and format
Option	_	_	TruMap (TruLine), AZtec Large Area Mapping, AZtec Feature, etc,
Size/weight			
Item	AZtec0ne	AZtecLiveOne	AZtecEnergy
Detector	145 (width) × 150 (depth) × 200 (height) mm	, 2.7 kg	
Analyzer unit	290 (width) × 260 (depth) × 330 (height) mm	, 10 kg	Mics F+; 180 (width) × 260 (depth) ×330 (height) mm, 2.6 kg
			X-stream2: 180 (width) × 260 (depth) ×330 (height) mm, 2.6 kg
Installation conditions			
Item	AZtec0ne	AZtecLiveOne	AZtecEnergy
	Single Phase AC, 100-240 V, 50/60 Hz, 400		Single-phase AC, 100-240 V, 50/60 Hz, 1,500 VA

TM4000Plus II / TM4000 II Specifications

Specifications		5 2007
Item	Descriptipn	
Model name	TM4000Plus II	TM4000 II
Model No.	TM4000Plus	TM4000
Magnifications	10x - 100,000x (Photogra 25x - 250,000x (Monitor d	
Accelerating voltage	5 kV, 10 kV, 15 kV, 20 kV*	3
lmage signal	Backscattered electron Secondary electron Mix (Backscattered electron+ Secondary electron)	Backscattered electron
Vacuum mode	BSE: Conductor/Standard/ Charge-up reduction SE: Standard/ Charge-up reduction Mix: Standard/ Charge-up reduction	BSE: Standard/ Charge-up reduction
Image mode (BSE)	Normal/Shadow 1/Shado	w 2/TOPO
Sample stage traverse	X: 40 mm, Y: 35 mm	
Maximum sample size	80 mm (diameter), 50 mr	m (thickness)
Electron gun	Pre-centered cartridge tur	ngsten filament
Signal detection system	High-Sensitivity 4-segment BSE detector High-Sensitivity Low- Vacuum SE detector (UVD)	High-Sensitivity 4-segment BSE detector
Auto image- adjustment function	Auto start, Auto focus, Aut	to brightness

 $2,560 \times 1,920$ pixels, $1,280 \times 960$ pixels, 640×480 pixels

Micron marker, micron value, magnification,

date and time, image number and comment, WD (Working Distance), accelerating voltage,

Raster rotation, Magnification presets (3 steps),

Over-current protection function, built-in ELCB

vacuum mode, image signal, image mode

Turbo molecular pump: 67 L/s x 1 unit Diaphragm pump: 20 L/min x 1 unit

Image shift (±50 µm @ WD6.0 mm)

■Required PC specifications

Item	Descrip	tipn
Model name	TM4000Plus II	TM400011
OS	Windows® 10 (64bit)	
Memory device	HDD, DVD-ROM Drive	

BMP, TIFF, JPEG

■Size/weight

Item	Item Description	
Model name	TM4000Plus II	TM4000 II
Main unit (motorized stage)	330 (width) × 614 (depth)	× 547 (height), 54 kg
Main unit (manual stage)	330 (width) × 617 (depth)	× 547 (height), 54 kg
Diaphragm pump	144 (width) × 270 (depth)	× 216 (height), 5.5 kg

■Optional accessories

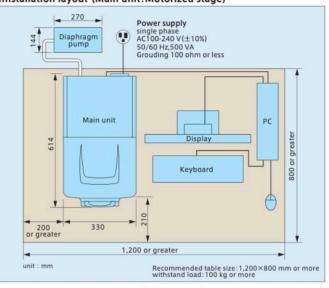
Tilt & rotation stage
Multi Zigzag function
Cooling stage
STEM holder

■Installation conditions

Item	Description	
Room temperature	15-30 °C (△t=within ±2.5°C/h or less)	
Humidity	- 70% RH (no condensation)	
Power supply (main unit)	Singlep phase AC100-240 V (fluctuations in voltage: ±10%)	

^{*}Another power souce for PC is required.

■Installation layout (Main unit: Motorized stage)



- *1 Defined at photo size of 127 mm×95 mm (4"×5" picture size)
- *2 Defined at display size of 317 mm×238 mm *3 There is a limit to the focus when using 20 kV
- *Please make room for more than 200 mm to the left side of a main unit
- and put it the closest to the center position of the table.

 *A table with caster is not suitable to put a main unit of TM4000 Series.
- * Please put a diaphragm pump under the table.

 * Periodical maintenance is required for this apparatus.
- *Powercables, earth terminal and table should be prepared by users.
- *TM4000 Series is not approved as a medical device. *Dedicated mentors, teachers who received the operation training of the instrument are required
- at compulsory schools. *It is advisable not to install or relocate the instrument by yourselves.
- *When relocating the system, please contact in advance the sales department that handles your account or a maintenance service company designated by Hitachi.
- *Screen shows simulated image.

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Science for a better tomorrow

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Notice: For correct operation, follow the instruction manual when using the instrument.

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